

FORM PTO-1449

ATTY. DOCKET NO.

SERIAL NO.

1201.64722

662,682  
09/30/2000LIST OF PATENTS AND PUBLICATIONS FOR  
APPLICANT'S INFORMATION DISCLOSURE  
STATEMENT

APPLICANT

Li et al.

FILING DATE

9/15/2000

(Use several sheets if necessary)

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JAN 11 2001

## REFERENCE DESIGNATION

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
LV	1A	4,092,445	May 30, 1978	Tsuzuki et al.		
LV	1B	5,139,624	Aug. 18, 1992	Searson et al.		
LV	1C	5,206,523	Apr. 27, 1993	Goesele et al.		
LV	1D	5,552,328	Sep. 3, 1996	Orlowski et al.		
LV	1E	5,767,020	June 16, 1998	Sakaguchi et al.		
LV	1F	5,970,361	Oct. 19, 1999	Kumomi et al.		
	1G					
	1H					
	1I					
	1J					
	1K					



## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	TRANSLATION	
							YES	NO
	1L							
	1M							
	1N							
	1O							
	1P							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

LV	1Q	D. Dimova-Malinovska, M. Sendova-Vassileva, N. Tzenov and M. Kamenova, "Preparation of Thin Porous Silicon Layers by Stain Etching", Thin Solid Films 297, 1997, pp. 9-12.
LV	1R	T. Monguchi, H. Fujioka, K. Ono, Y. Baba, M. Oshima, "Effects of Wet Etching on Photoluminescence of Porous Silicon", Journal of the Electrochemical Society, Vol. 147, No. 2, 2000, pp. 602-605.
LV	1S	J. Salonen, V. Lehto, M. Bjorkqvist, E. Laine, "A Role of Illumination During Etching to Porous Silicon Oxidation", Applied Physics Letters, Vol. 75, No. 6, August 9, 1999, pp. 826-828.

EXAMINER

DATE CONSIDERED

LAN VJNH

12/3/2001

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LIST OF PATENTS AND PUBLICATIONS FOR  
APPLICANT'S INFORMATION DISCLOSURE  
STATEMENT

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ATTY. DOCKET NO.

1201.64722

SERIAL NO.

1201.64722  
09,660,611

APPLICANT

Li et al.

FILING DATE

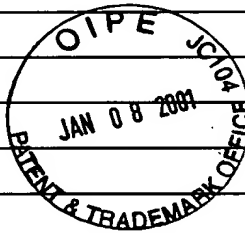
9/15/2000

GROUP

## REFERENCE DESIGNATION

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
	2A				
	2B				
	2C				
	2D				
	2E				
	2F				
	2G				
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	2J				
	2K				

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## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	TRANSLATION	
						YES	NO
	2L						
	2M						
	2N						
	2O						
	2P						

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

LV	2Q	T. Tsuboi, T. Sakka, Y.H. Ogata, "Chemical Etching of Porous Silicon in Diluted Hydrofluoric Acid", Solid State Communications, Vol. 109, 1999, pp. 195-199.
	2R	
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